

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application Serial No. .... 08/846,671  
Filing Date ..... April 30, 1997  
Inventor ..... Kei-Yu Ko  
Assignee..... Micron Technology, Inc.  
Group Art Unit..... 1763  
Examiner ..... George Goudreau  
Attorney's Docket No. .... MI22-2041  
Title:       Undoped Silicon Dioxide as Etch Stop for Selective Etch of  
              Doped Silicon Dioxide

**RESPONSE TO MARCH 3, 2003 CONFERENCE WITH EXAMINER AND  
SUPPLEMENTAL RESPONSE TO DECEMBER 5, 2002 OFFICE ACTION**

To:       Commissioner for Patents  
          Washington, D.C. 20231

**VIA EXPRESS MAIL**

From:   Mark Matkin (Tel. 509-624-4276; Fax 509-838-3424)  
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Responsive to the Conference with the examiner, held on March 3,  
2003, Applicant amends and remarks as follows:

**AMENDMENTS**